

Deposition of stoichiometric VO₂ on ultra-thin glass in roll-to-roll process

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Introduction

Vanadium dioxide (VO₂) exhibits different polymorphic structures, among them monoclinic VO₂(B) and VO₂(M1), which are widely studied in science and technology development for their application potential: VO₂(B) can be used as e.g. electrode materials for batteries and VO₂(M1) as thermochromic layer for Insulating Glass Units (IGU). Through reversible, temperature-dependent semiconductor-to-metal

transition (at the switching temperature T_{tr}) of low-temperature monoclinic VO₂(M1) to high-temperature tetragonal VO₂ (R); electrical and optical properties are changed. Especially the transmission in infrared (IR) wavelength range can be significantly reduced. Such thermochromic behaviour can lead to a reduction of the energy consumption of buildings, particularly for cooling.

Methods

- Challenging technology transfer from a laboratory-scale (University of West Bohemia) to roll-to-roll process on FOSA labX 330 glass coater (Fraunhofer FEP, Figure 1)
- Deposition of ZrO₂ bottom and top layer from ceramic ZrO_x target with unipolar pulsed direct current magnetron sputtering
- Deposition of thermochromic monoclinic VO₂ (M1) with high-power impulse magnetron sputtering (HiPIMS) from V target doped with W (1.5 at%), using a pulsed O₂ flow control (Vlcek group, University of West Bohemia - UWB).
- Deposition of non-thermochromic monoclinic VO₂ (B) with unipolar pulsed direct current magnetron sputtering from V target doped with W (1.5 at%)
- Substrate: ultra-thin glass (100 µm thickness, 300 mm width)

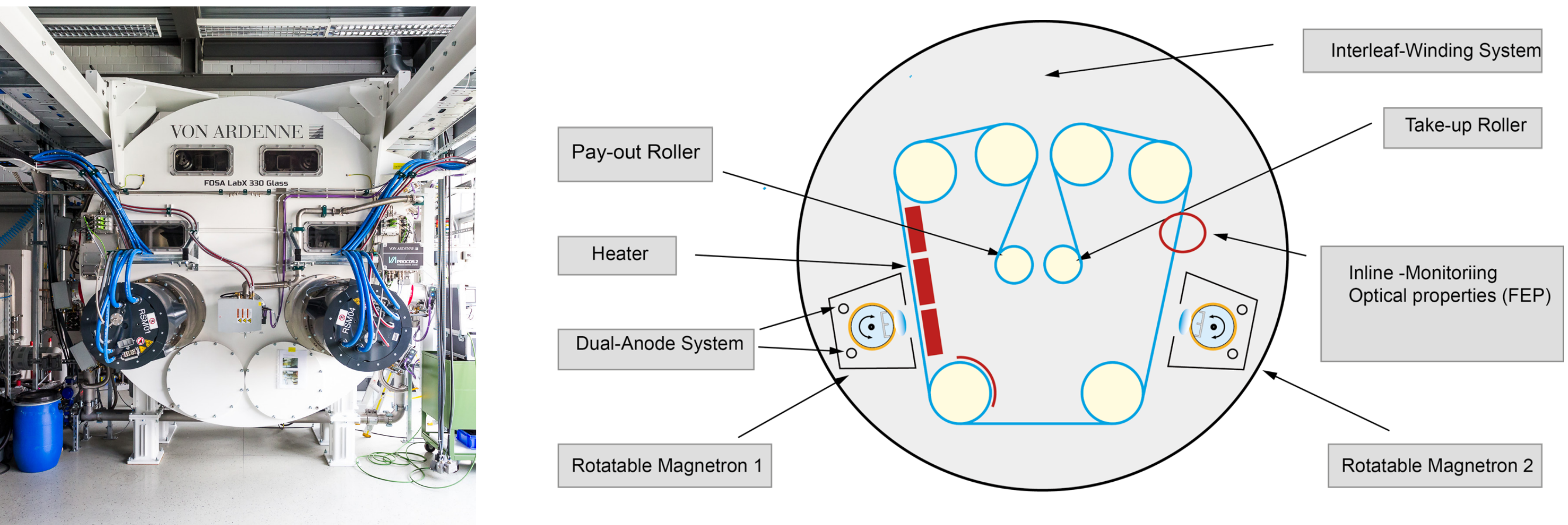
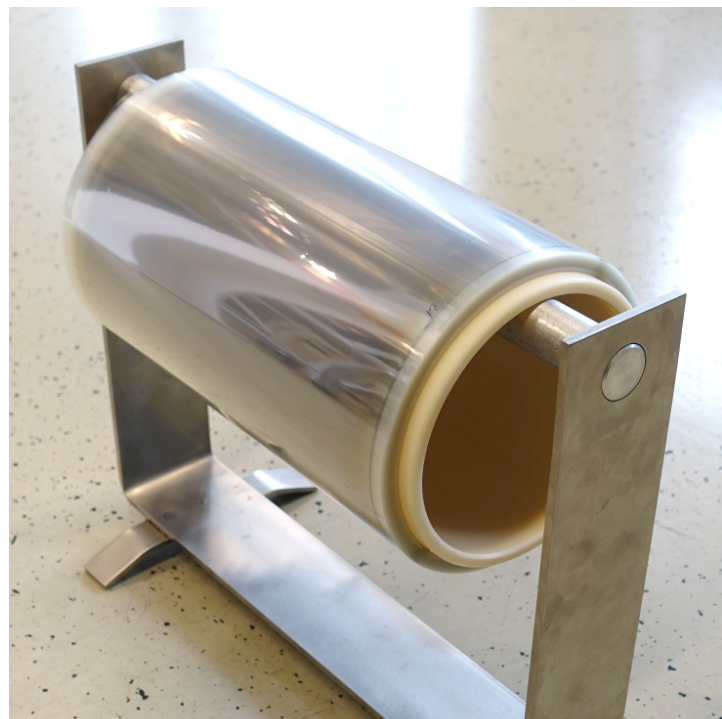


Figure 1: Scheme of the FOSA labX 330 glass coater.



UWB (batch process)

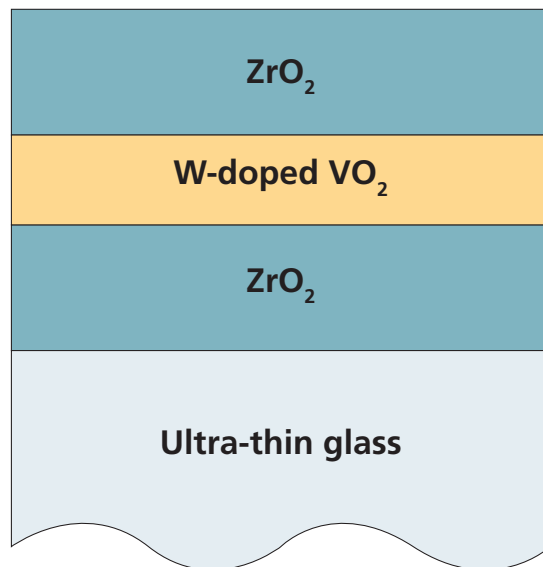
Planar target, 50 mm diameter
Substrate fixed on rotating holder
V target, W target, W amount, variable, co-sputtering
2.5 cm × 5 cm sheet substrates
Up to 4 different compounds in one run

Fraunhofer FEP (roll-to-roll)

Tube target, 665 mm length
Moving substrate (dynamic process)
V target doped with W (fixed amount of W)
300 mm × 20 m roll substrates
2 different compounds in one run possible

Three-layer system:

- ZrO₂ bottom and top layer → optimal optical properties
- ZrO₂ bottom layer → seed layer
- ZrO₂ top layer → mechanical and chemical protection
- VO₂ → active layer
- Doping of W → decrease in switching temperature



Results: Crystalline Structure

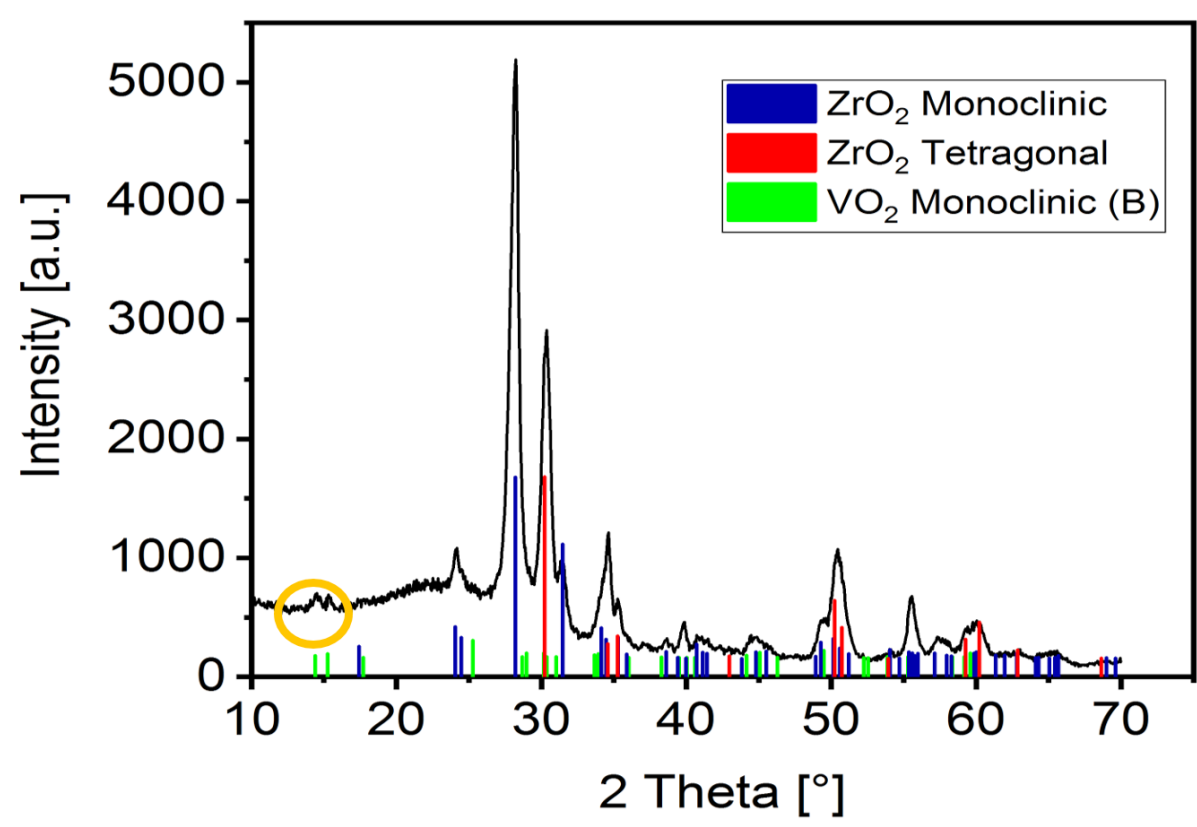


Figure 2: GIXRD spectrum of ZrO₂/V_{1-x}W_xO₂ with the monoclinic VO₂(B) on ultra-thin glass.

- ZrO₂ structure: monoclinic and tetragonal → suitable as a seed layer for VO₂
- VO₂ structure: single phase monoclinic (B), Figure 2, and dominant tetragonal (R) with thermochromic properties, Figure 3

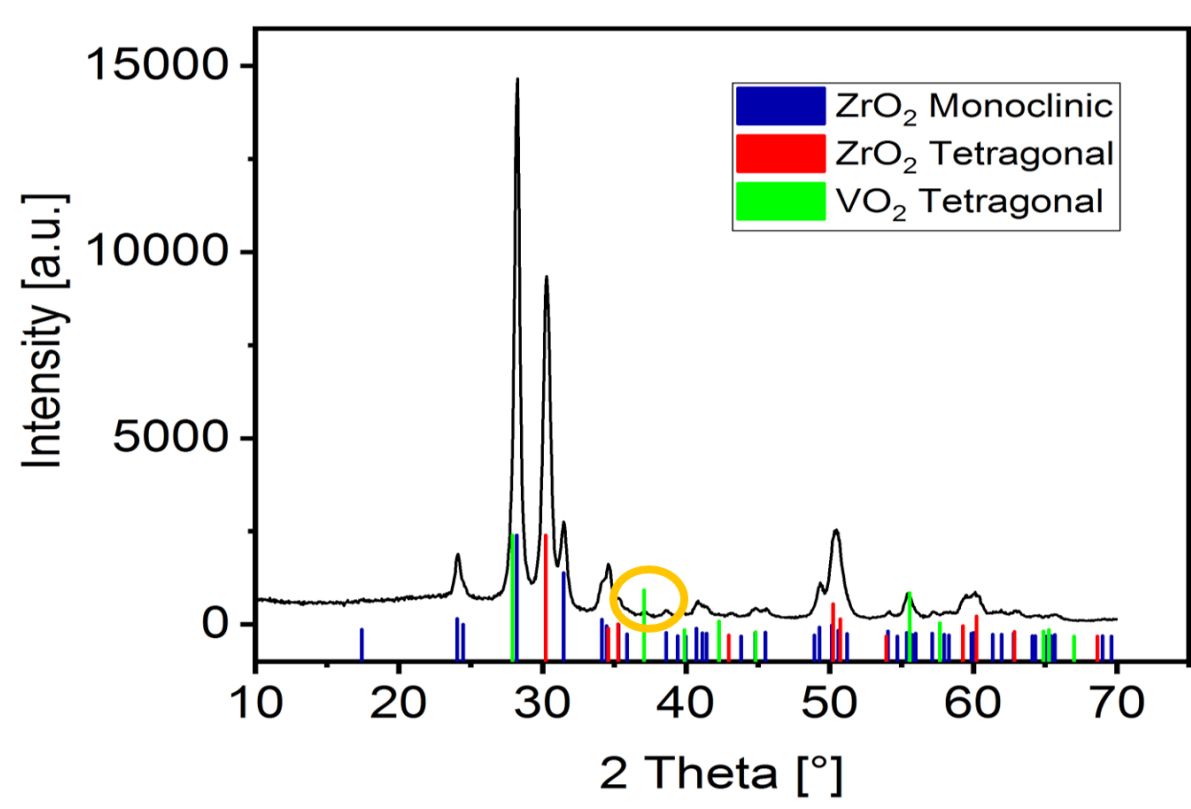
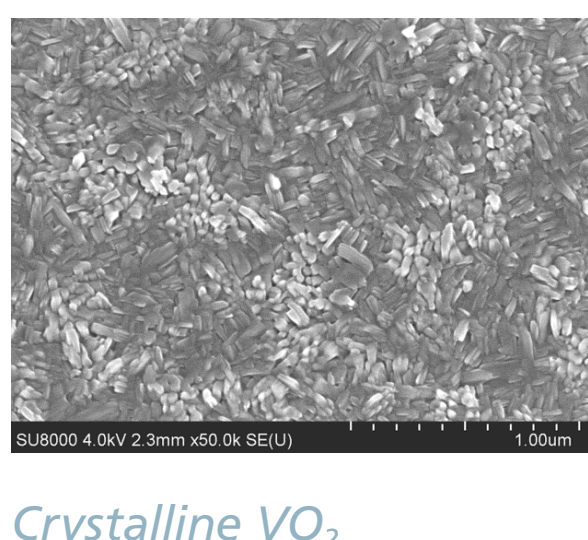


Figure 3: GIXRD spectrum of ZrO₂/V_{1-x}W_xO₂/ZrO₂ with the dominant tetragonal VO₂ (R) on ultra-thin glass.

Optical Properties

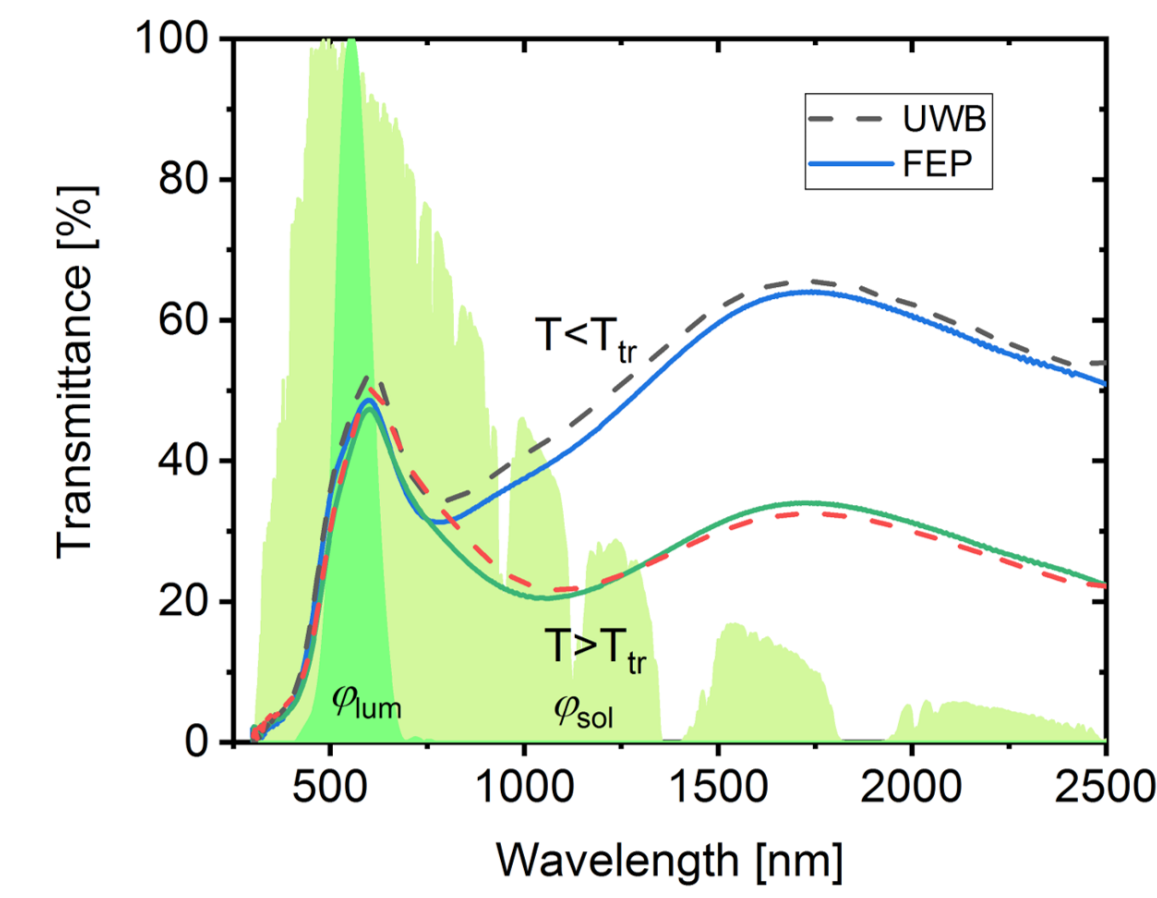


Figure 4: Spectral transmittance for thermochromic ZrO₂/V_{1-x}W_xO₂/ZrO₂ coatings on 0.1 mm ultra-thin glass at a low (blue lines) and high (red lines) temperature. Dashed lines for a sample prepared at the UWB, solid line at the FEP.

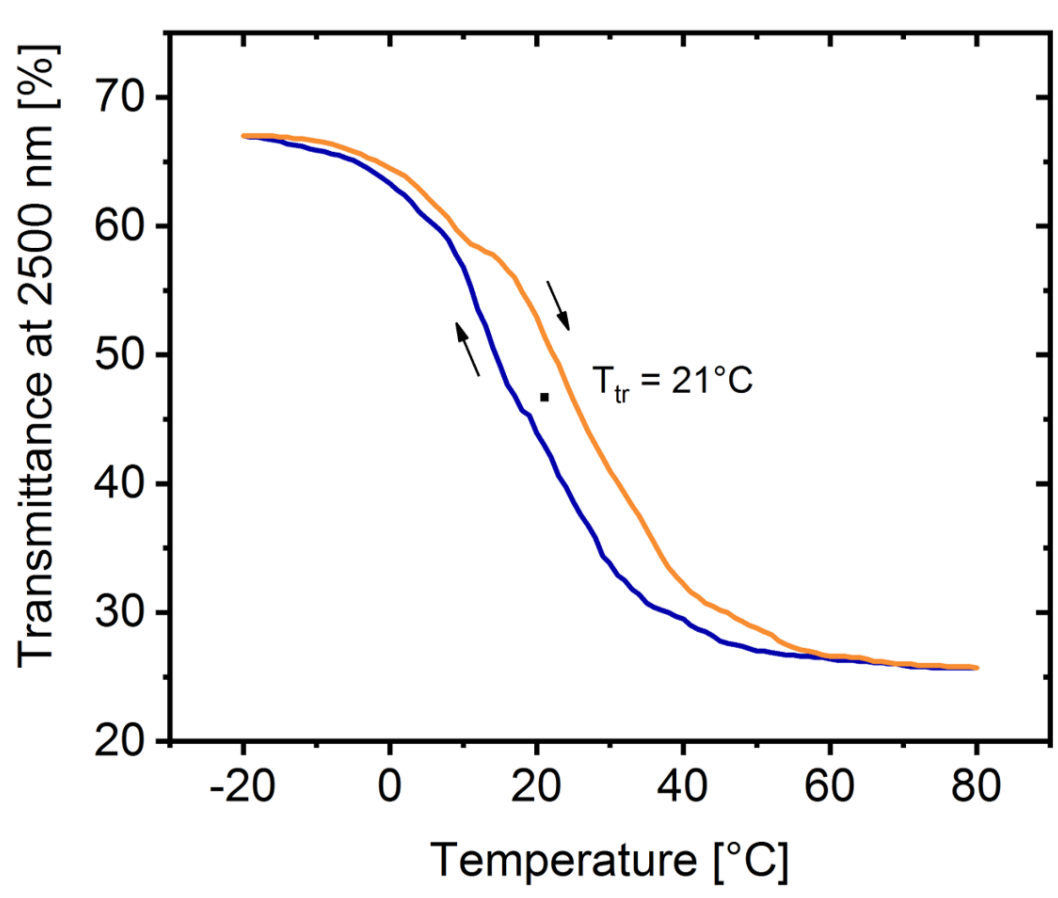


Figure 5: Temperature dependence of the transmittance at 2500 nm for the ZrO₂/V_{1-x}W_xO₂/ZrO₂ film coating on ultra-thin glass deposited in R2R. The switching temperature is presented.

*Barta et. al., Coatings 2020, 10, 1258; doi:10.3390/coatings10121258

Conclusion

The worldwide first thermochromic VO₂-based coatings on ultra-thin glass were deposited in roll-to-roll process with HiPIMS. The comparable optical properties between the results from Fraunhofer FEP and UWB show the successful transfer of sputter deposition technique from the laboratory-scale

- Significant drop in the transmittance crossing the switching temperature (Figure 4)
- Evaluation of the switching temperature to 21 °C (Figure 5)
- Comparable results to the coatings in laboratory-scale at UWB

Parameter set for deposition of VO₂ at UWB

- Power density: 13.5 W/cm²
- Voltage pulse duration: 80 µs
- Frequency: 625 Hz
- Deposition temperature: 330 °C

	T _{lum} ^{**} [%]	ΔT _{sol} [%]	T _{tr} [°C]
UWB	44.0	9.6	22
FEP-R2R	41.9	8.7	21

**The presented measured values of T_{lum} are underestimated by up to 4 %.

to roll-to-roll coater and a very good upscaling possibility for preparation of thermochromic VO₂-based coatings in large area production.

Process Parameters

	ZrO ₂	W-doped VO ₂
Power	6 kW	6 kW
Pulse on	16 µs	70 µs
Frequency	50 kHz	750 Hz
Pressure	0.38 Pa	0.20 – 0.22 Pa
Band speed	0.15 m/min	0.10 m/min
O ₂ flow	8 sccm	0 – 50 sccm

O₂ Flow Control

$$p_{ox}(t) \geq (p_{ox})_{crit} \rightarrow \Phi_{ox}(t) = 0,$$

$$p_{ox}(t) < (p_{ox})_{crit} \rightarrow \Phi_{ox}(t) = \Phi_{ox} \neq 0$$

- Pulsed O₂ inlet system
- O₂ inlet orientation towards the substrate
- O₂ inlet location in the dense plasma in front of the sputtered target

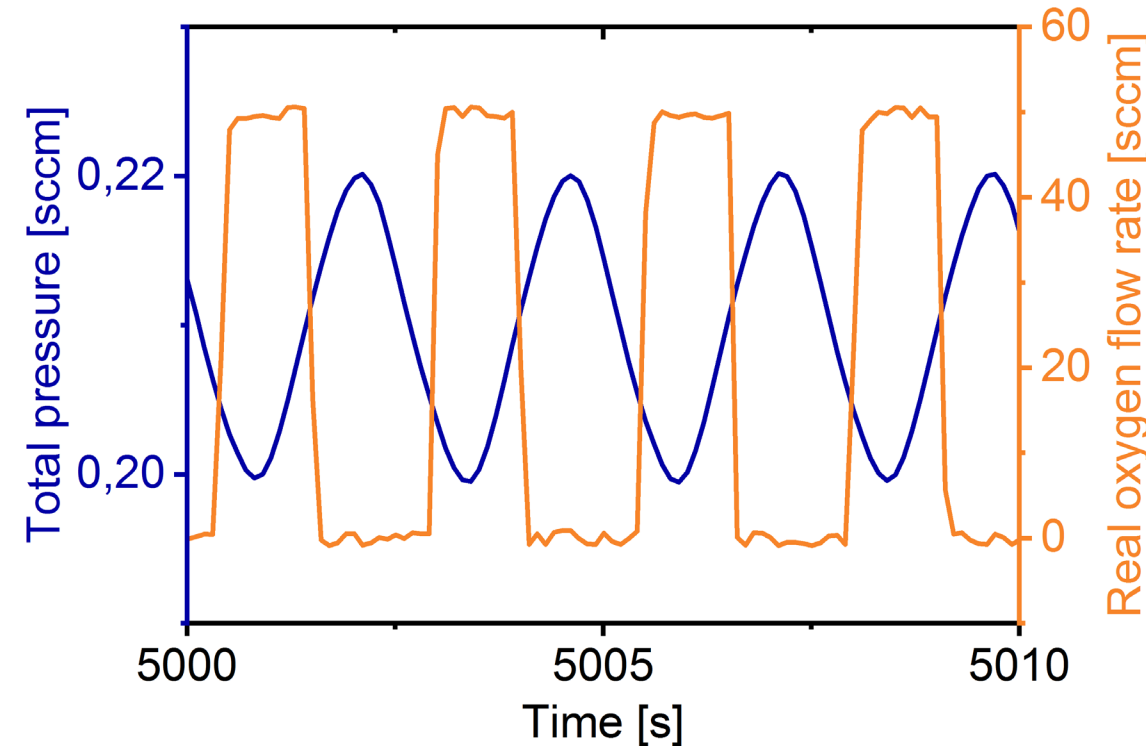


Figure 6: Time evolution of the total pressure and the corresponding oxygen flow pulses during a HiPIMS deposition of W-doped VO₂ layers.

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